

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Brian Fletcher on 2/26/2007.

The application has been amended as follows: A brief description of the figures to be inserted between lines 23 and 24 of page 7 of SPEC (11/23/2003):

BRIEF DESCRIPTION OF THE FIGURES

FIG. 1A shows an example laser system of the present invention.

FIG. 1B shows the detailed liquid crystal tunable filter used in FIG. 1A.

FIG. 2 shows an example waveguide grating optical filter of the present invention.

FIG. 3 shows an example tunable filter passband output profile as a function of index of refraction.

FIG. 4A shows an example wavelocker flow cycle of the present invention.

FIG. 4B shows an example waveform reflected passband and transmitted complement of the present invention.

FIG. 5 shows one process flow for fabricating the tunable filter of the present invention.

FIGS. 6A and 6B show four pixel indium tin oxide (ITO) electrode forming masks of the present invention.

FIGS. 7A and 7B show example integrated active thermal element forming masks of the present invention.

FIGS. 8A and 8B show example spacer element forming masks of the present invention

FIGS. 9A - 9E show example masks for defining a metal gasket element layer of the present invention.

FIG. 10A shows an example top view integrated perspective showing the relationship between various layers of a one dimensional (1.times.N) array configuration of the present invention.

FIG. 10B is an isometric view showing a nine pixel (N.times.M) two dimensional liquid crystal cell at the termination of the fabrication process.

FIG. 11 shows the liquid crystal thermal calibration and feedback loop method flows.

FIG. 12 shows a block system diagram for the electronic control and thermal management system of the present invention.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Phu Vu whose telephone number is (571)-272-1562. The examiner can normally be reached on 8AM-5PM M-F.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on (571)-272-1787. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

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